

Emission Sources - Maximum Allowable Emission Rates

Permit Number 75930L001

This table lists the maximum allowable emission rates and all sources of air contaminants on the applicant's property covered by this permit. The emission rates shown are those derived from information submitted as part of the application for permit and are the maximum rates allowed for these facilities, sources, and related activities. Any proposed increase in emission rates may require an application for a modification of the facilities covered by this permit.

Air Contaminants Data

Emission Point No. (1)	Source Name (2)	Air Contaminant Name (3)	Emission Rates (6)	
			lbs/hour	TPY (4)
10	Crusher #1 (5)	PM	0.18	0.11
		PM ₁₀	0.08	0.05
		PM _{2.5}	0.02	0.01
4	Screen #1 (5)	PM	0.20	0.13
		PM ₁₀	0.07	0.04
		PM _{2.5}	0.01	0.01
7	Screen #2 (5)	PM	0.18	0.11
		PM ₁₀	0.06	0.04
		PM _{2.5}	0.01	0.01
9	Screen #3 (5)	PM	0.08	0.05
		PM ₁₀	0.03	0.02
		PM _{2.5}	<0.01	<0.01
1-3, 5-6, 8, 11-14	Material Handling (Hoppers, Conveyors & Screen Drop-Off Points) (5)	PM	0.44	0.27
		PM ₁₀	0.15	0.09
		PM _{2.5}	0.04	0.02
STK	Stockpiles (5)	PM	--	3.08
		PM ₁₀	--	1.54
		PM _{2.5}	--	0.23

- (1) Emission point identification - either specific equipment designation or emission point number from plot plan.
- (2) Specific point source name. For fugitive sources, use area name or fugitive source name.
- (3) PM
 - total particulate matter, suspended in the atmosphere, including PM₁₀ and PM_{2.5}, as represented
 - PM₁₀
 - total particulate matter equal to or less than 10 microns in diameter, including PM_{2.5}, as represented
 - PM_{2.5}
 - particulate matter equal to or less than 2.5 microns in diameter
- (4) Compliance with annual emission limits (tons per year) is based on a 12-month rolling period.
- (5) Emission rate is an estimate and is enforceable through compliance with the applicable special condition(s) and permit application representations.
- (6) Planned startup and shutdown emissions are included. Maintenance activities are not authorized by this permit.

Date: February 21, 2020